

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	Confirmation No.: 5877
Kenichi MORIMOTO	Art Unit: 1763
S. N. 10/737,393	Examiner: Allan W. Olsen
Filed: December 16, 2003	

For: MASK BLANK FOR CHARGED PARTICLE BEAM EXPOSURE, METHOD OF  
FORMING MASK BLANK AND MASK FOR CHARGED PARTICLE BEAM EXPOSURE

RESPONSE TO OFFICE ACTION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the office action dated July 16, 2007, for which a two month extension of time is requested to extend the period for response to Monday, December 17, 2007, please make the following amendments:

Claim amendments begin on page 2 of this document.

Remarks begin on page 4 of this document.